



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Applicant: Steven R. Walther
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For: Method and Apparatus for Controlling Ion Implantation During Vacuum Fluctuation
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The undersigned hereby certifies that this document is being placed in the United States mail with first-class postage attached, addressed to Commissioner for Patents, Washington, D.C. 20231 on September 27, 2001.

[Signature]
Lisa A. Fletcher

Attn: Official Draftsperson
Commissioner for Patents
Washington, DC 20231

LETTER TO OFFICIAL DRAFTSPERSON

Sir:

In response to the Notice of Allowability dated July 2, 2001, enclosed are four (4) sheets of FORMAL DRAWINGS for Figures 1-4 for the above-referenced patent application.

Respectfully Submitted,

[Signature]

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